Precise and ultra-stable laser polarization control for polarized electron beam generation

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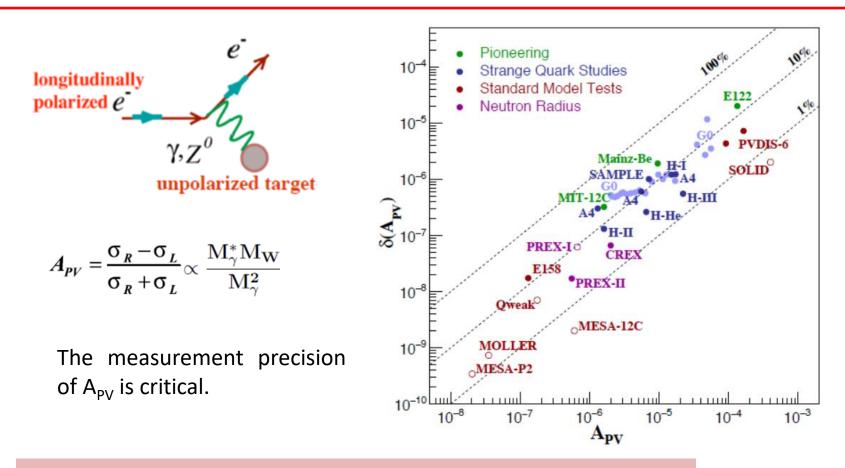
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Outline

- Background and Motivations
- Project Task and Technical Approach
- Progress and Results

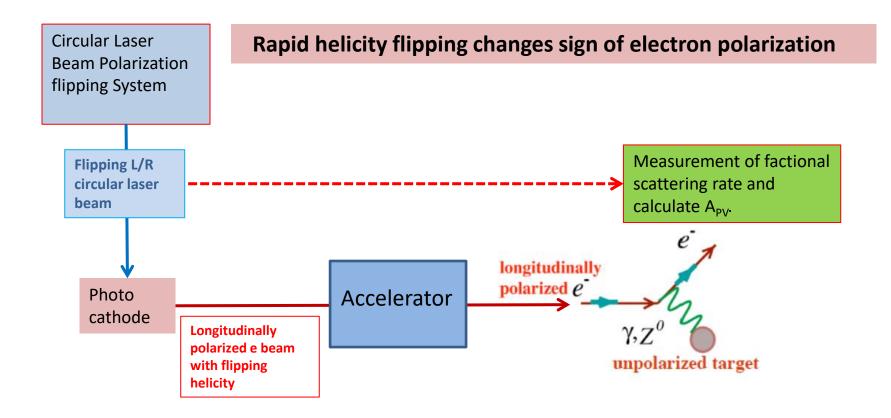


Background and Motivation



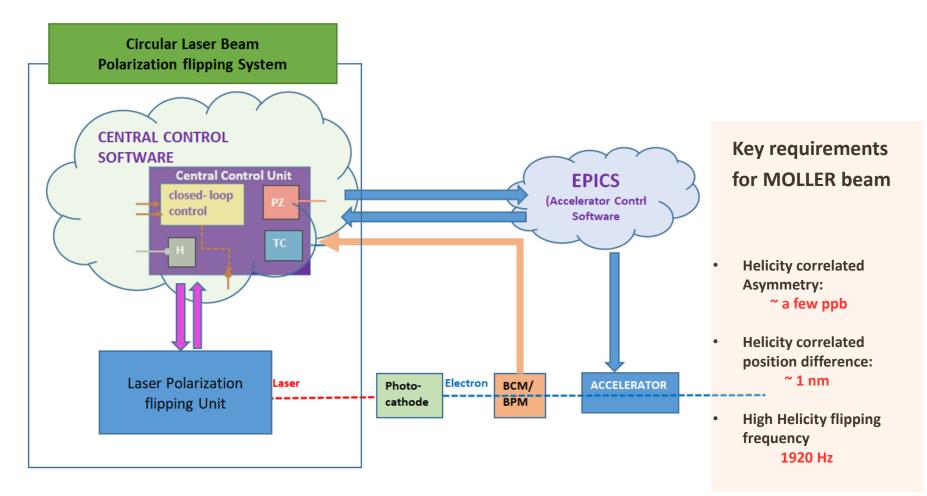
The properties of the incident electrons shall remain identical except the sign of polarization, but they tends to change due to various factors...

Circular Laser beam Polarization Flipping System in PVES



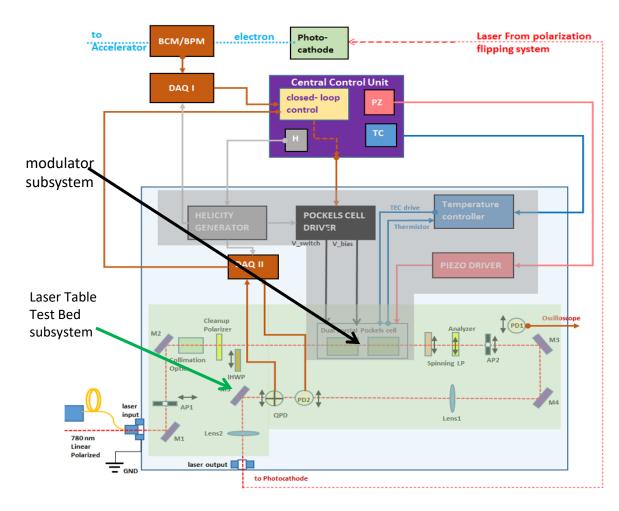
The helicity correlated asymmetry causes uncertainty to the measurement of A_{PV}

Technical Approach



Circular Polarization Flipping System

Technical Approach



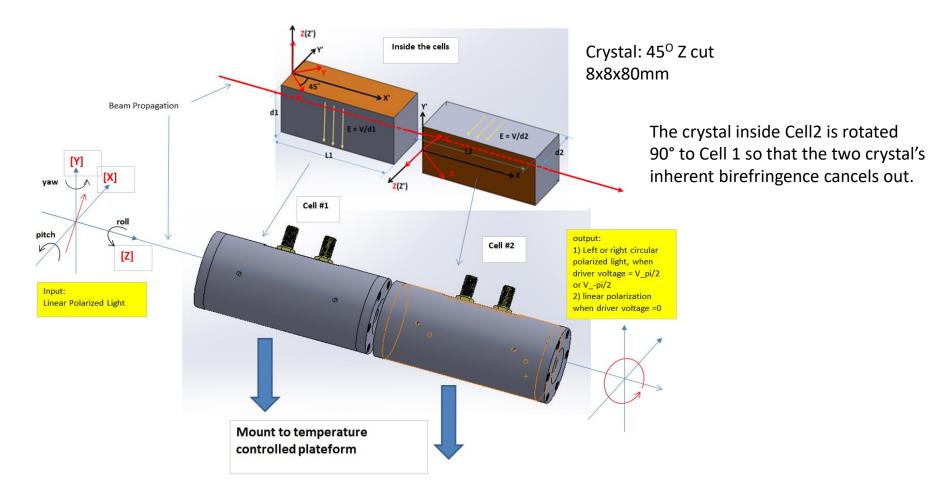
Parameter	Specification		
Repetition rate	1920 Hz		
Duty cycle	>95%		
Spot size asymmetry (RMS)	< 10-4		
Position difference (no analyzer)	< 200 nm		
Position difference (S1 or S1analyzer)	< 400 nm		
Intensity noise	< 100 ppm		
4-peak asymmetry	< 7,000 ppm		
HC intensity asymmetry	< 500 ppm	1	
Lifetime*	> 10,000 hrs	•	

Schematic of Circular Polarization Flipping Laser Beam Unit

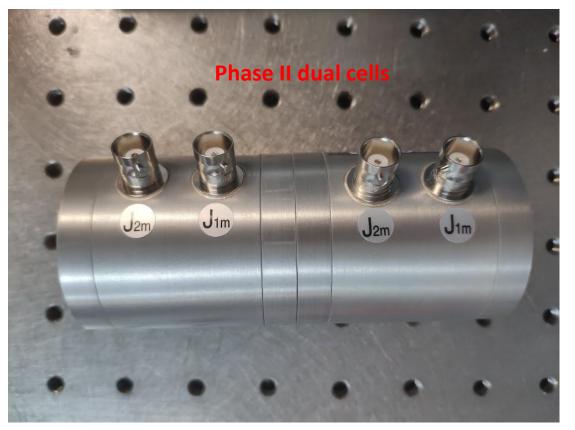


Pockels Cell Design

Modulator Subsystem – Dual DKDP Pockels cell design

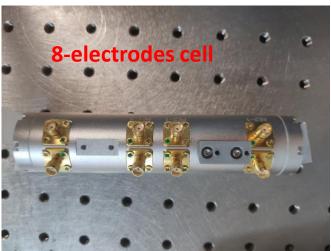


DKDP Pockels Cell Prototypes



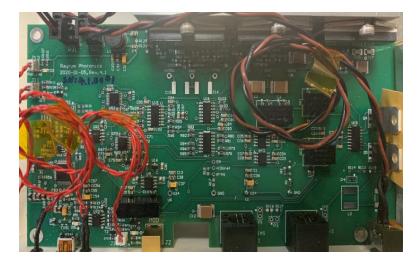
We designed several Pockels cells for testing and development of Phase I and Phase II.



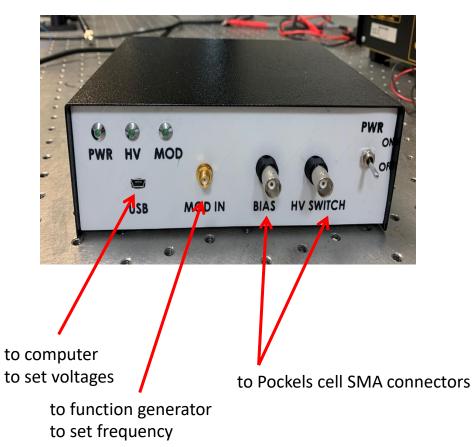


High Voltage Driver

High Voltage Diver PC board

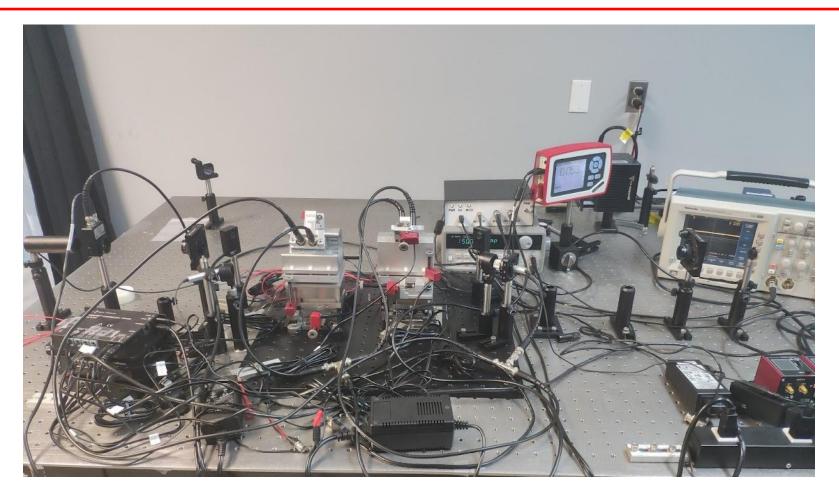


Modulator Diver front panel



- digital bi-level highpower switching design
- 5.5 mV resolution with precise voltage reference
- Rise time and ringing compromise

Test Bed



We also designed mount for Pockels cell with 5 axis Piezo-driver precise position control.

Testing with the Dual cell on the mount

Targeted Modulator Subsystem Specification

Parameter	Specification		
Clear aperture	8 mm		
PER	>30 dB		
Driving voltage (@780 nm, V± _{π/2})	± 250V		
Bias voltage	< 50V		
Voltage resolution	0.01V		
Operation frequency	1920 Hz		
Residual linear polarization	< 5%		
Settle time	< 25 us		
Ringing variation after settle time	Within ± 10%		
Temperature stability	Within ± 0.005°C		
Translation resolution	XY: 1 um, Z: 0.1 mm		
Angle resolution	Pitch, Yaw: 50 urad, piezo Roll: 0.5 mrad, manual		

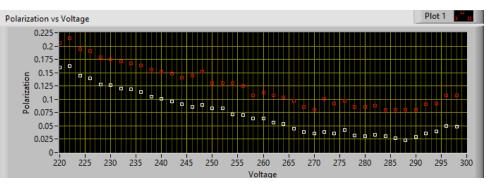
Improvement from Phase I

- Dual crystal configuration with active individual cell alignment to cancel out inherent birefringence
- Improve transition performance by optimizing driver design
- Use Large beam size /Crystal size
- Closed loop control
- Implement better X/Y and Pitch/Yaw scan

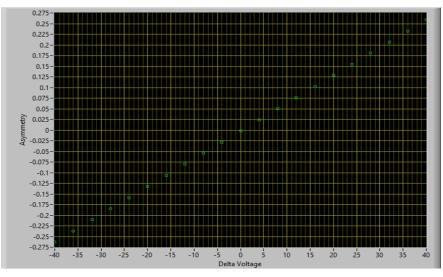
Same as in Phase I.

• Precise temperature control

Performance (I)



We achieve a residual linear polarization \sim 2.5% during test on the DKDP dual cell system.



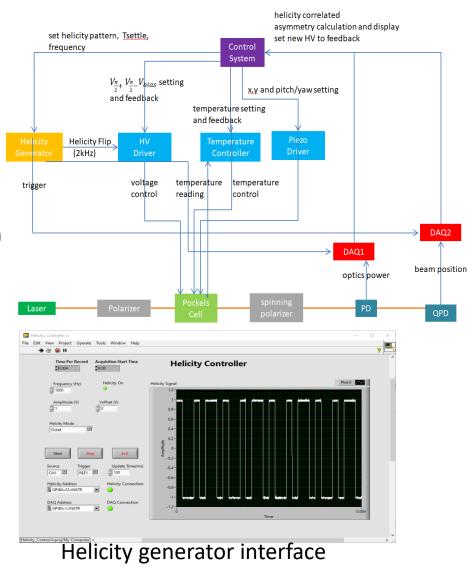
In our test we find the PITA slope is 6525 ppm/V, which is close to the prediction from the equation, 6280 ppm/V.

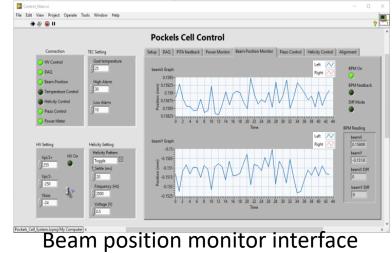
Plot 0 📈 XY Graph 0.375 0.35 0.325-0.3 0.275-0.25 0.225-0.225-0.2-0.175-0.15-0.15 0.125 0.1 0.075 0.05 0.025 0 -300 -200 -100 100 200 300 400 -500 -400 0 500 V Pmin Pmax Wave Scan 0.351463 0.000304 Vmax Vmin 480 -50 PER PO 0.008268 1152.38

PER ~ 1000

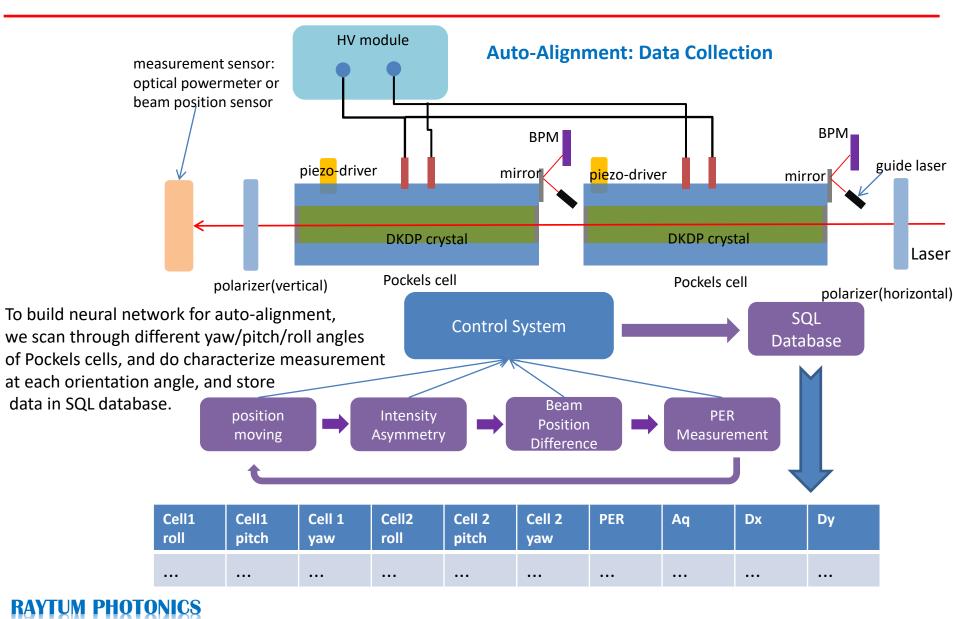
Control Software Development Using Machine Learning Technology

- Control Software Development:
- Helicity generator
- HV driver
- Temperature controller
- Piezo driver
- Optical power monitor
- Beam position monitor
- Auto-Alignment Module/Data Collection

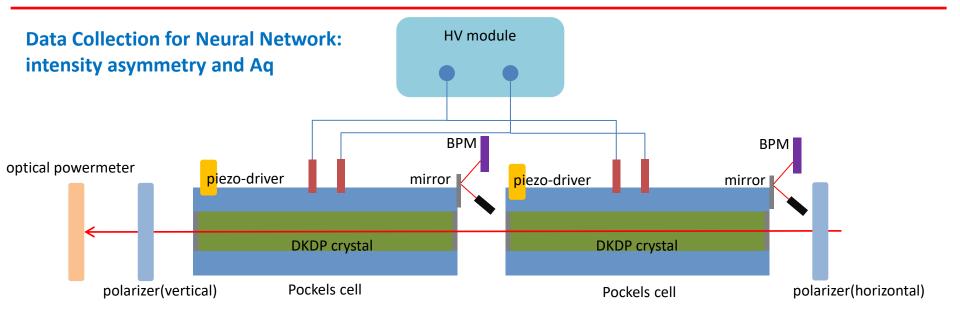


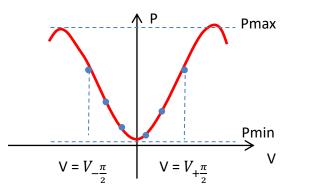


System Description



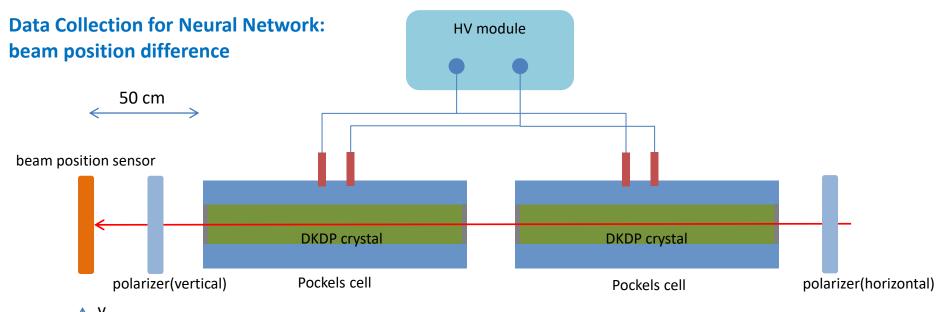
Data Collection I

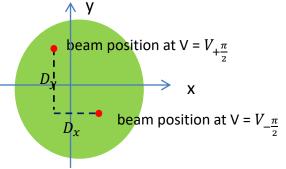




At each Pockels Cell orientation angle, we collect data for PER : scan voltage applied on cell from -500 V to 500 V, PER = Pmax/Pmin intensity asymmetry: asymmetry of optical intensity of two polarization states.

Data Collection II





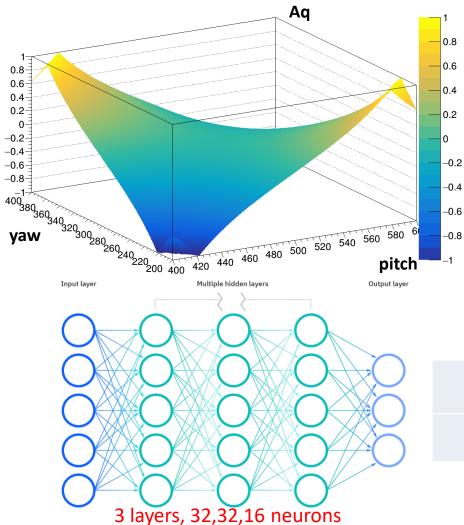
To measure beam position difference at every Pockels cell orientation angle:

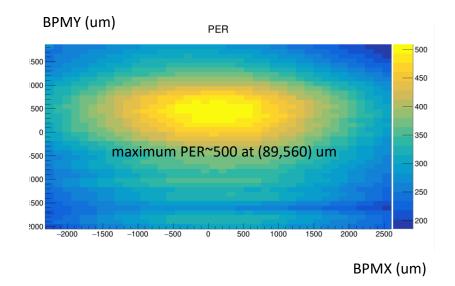
We place a beam position sensor 50 cm downstream of the Pockels cell.

we measure beam position at two polarization states, then do the difference to get Dx and Dy.

To reduce the uncertainty, we repeat the measurement several times.

Progress and Results



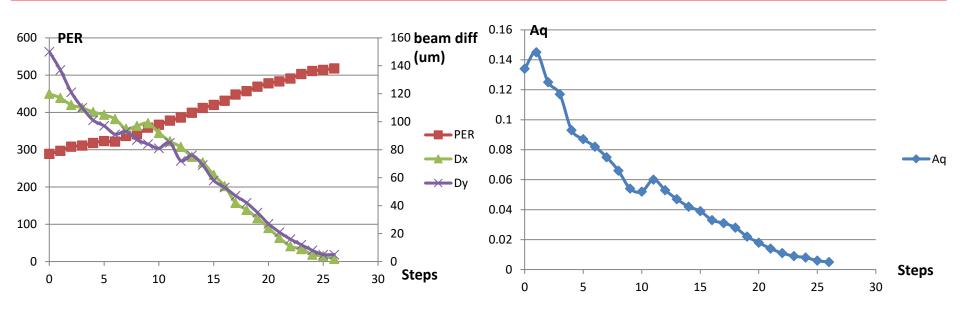


Mean error of built neural network

Model	PFR	Aq (Intensity asymmetry)	Dx (beam position difference in x)	• •
ANN	4.8%	4.1%	3.8%	3.2%

Base on neural network build from data collection, we can build a 3 layer neural network with very good precision.

Progress and Results



Here is the result of auto-alignment:

We start with a state PER = 289, Aq(intensity asymmetry)=0.134, Dx (beam position diff in x) = 121 um, Dy (beam position diff in y) = 150 um,

after 28 steps, we reach the optimal position with PER = 512, Aq = 0.005, Dx = 2 um, Dy = 5 um.

The total auto-alignment process takes ~ 30 min.

Thank you! Questions?

